Ref · #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	231	(Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holder or holding or housing or carrier)))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/02/02 10:31
L2	. 2	(Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or carrier)) with surfactant)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/02/02 10:33
13	105	(Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or carrier))) same (dust\$3 or particle or particulate or contamin\$8)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/02/02 10:36
L4	185	L1 not L3	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/02/02 10:36
L5	12	(Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer)_with ((wafer or_chip or	US-PGPUB; USPAT; EPO; JPO; DERWENT; -IBM_TDB	OR	ON	2005/02/02 10:37
	magan-addresser-in. Desirable 2 to	substrate or disc or disk) near3 (cassette)))			# 2 5	

	· · · · · · · · · · · · · · · · · · ·			· · ·		·
L6	9	((Munakata.in. or (Shin adj Etsu). as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (cassette)))) not (((Munakata.in. or (Shin adj Etsu). as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or carrier)))) not ((Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holding or housing or case or box or holding or housing or carrier))) same (dust\$3 or particle or particulate or contamin\$8)))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/02/02 10:37
L 7	19	(Munakata.in. or (Shin adj Etsu).as.) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (transport\$6)))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/02/02 10:38
L8	1247	(427/230,235).CCLS.	US-PGPUB; USPAT; USOCR	OR	OFF	2005/02/02 10:38
L9	1188	(427/352,353,354).CCLS.	US-PGPUB;	OR	OFF	2005/02/02 10:38
			USPAT; USOCR			
L10	5013	(427/372.2,379,384).CCLS.	US-PGPUB; USPAT; USOCR	OR	OFF	2005/02/02 10:38
L11	1750	(427/430.1).CCLS.	US-PGPUB; USPAT;	OR	OFF	2005/02/02 10:38
157			USOCR			
L12	930	(438/125).CCLS.	US-PGPUB; USPAT; USOCR	OR	OFF	2005/02/02 10:39
L13	4041	(206/308.1,524.1,524.6,525,526, 832).CCLS.	US-PGPUB; USPAT; USOCR	OR	OFF	2005/02/02 10:39
L14	856	(206/524.3).CCLS.	US-PGPUB; USPAT; USOCR	OR	OFF	2005/02/02 10:39

	,	<u> </u>				
L15	11393	((427/230,235).CCLS.) ((427/352, 353,354).CCLS.) ((427/372.2,379, 384).CCLS.) ((427/430.1).CCLS.) ((438/125).CCLS.) ((206/308.1,524. 1,524.6,525,526,832).CCLS.) ((206/524.3).CCLS.)	US-PGPUB; USPAT	OR	ON	2005/02/02 10:39
L16	23	(((427/230,235).CCLS.) ((427/352, 353,354).CCLS.) ((427/372.2,379, 384).CCLS.) ((427/430.1).CCLS.) ((438/125).CCLS.) ((206/308.1,524. 1,524.6,525,526,832).CCLS.) ((206/524.3).CCLS.)) and ((wafer or semiconductor) same (surfactant))	US-PGPUB; USPAT	OR	ON	2005/02/02 10:39
L17	0	((206/524.3).CCLS.) and ((wafer or semiconductor) same (surfactant))	US-PGPUB; USPAT	OR	ON	2005/02/02 10:40
L18	42	((206/524.3).CCLS.) and ((surfactant))	US-PGPUB; USPAT	OR	ON	2005/02/02 10:40
L19	0	(((206/524.3).CCLS.) and ((surfactant))) and (wafer or semiconductor)	US-PGPUB; USPAT	OR	ON	2005/02/02 10:41
L20	474	(((427/230,235).CCLS.) ((427/352, 353,354).CCLS.) ((427/372.2,379, 384).CCLS.) ((427/430.1).CCLS.) ((438/125).CCLS.) ((206/308.1,524. 1,524.6,525,526,832).CCLS.) ((206/524.3).CCLS.)) and ((coat\$3 or deposit\$3 or film or layer or immers\$5 or soak\$3 or dip or dipped or dipping or submer\$8) with surfactant)	US-PGPUB; USPAT	OR	ON	2005/02/02 10:41
L21	164	((((427/230,235).CCLS.) ((427/352, 353,354).CCLS.) ((427/372.2,379, 384).CCLS.) ((427/430.1).CCLS.) ((438/125).CCLS.) ((206/308.1,524. 1,524.6,525,526,832).CCLS.) ((206/524.3).CCLS.)) and ((coat\$3 or deposit\$3 or film or layer or immers\$5 or soak\$3 or dip or dipped or dipping or submer\$8) with surfactant)) and (dust\$3 or contamin\$8)	US-PGPUB; USPAT	OR	ON	2005/02/02 10:41

L22	59	((((427/230,235).CCLS.) ((427/352, 353,354).CCLS.) ((427/372.2,379, 384).CCLS.) ((427/430.1).CCLS.) ((438/125).CCLS.) ((206/308.1,524. 1,524.6,525,526,832).CCLS.) ((206/524.3).CCLS.)) and ((coat\$3 or deposit\$3 or film or layer or immers\$5 or soak\$3 or dip or dipped or dipping or submer\$8) with surfactant)) and (((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holder or holding or housing or carrier or cassette or transport\$6)))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/02/02 10:43
L23	7	((206/524.3).CCLS.) and (((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holder or holding or housing or carrier or cassette or transport\$6)))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/02/02 10:49
L24	95	((((427/230,235).CCLS.) ((427/352, 353,354).CCLS.) ((427/372.2,379, 384).CCLS.) ((427/430.1).CCLS.) ((438/125).CCLS.) ((206/308.1,524. 1,524.6,525,526,832).CCLS.) ((206/524.3).CCLS.)) and ((coat\$3 or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holder or holding or housing or carrier)))) and ((prevent\$5 or eliminat\$5 or reduc\$6 or lower\$3 or stop\$4) near3 (dust\$3 or particle or particulate or contamin\$8))	US-PGPUB; USPAT	OR	ON	2005/02/02 10:51
L26	308	(((427/230,235).CCLS.) ((427/352, 353,354).CCLS.) ((427/372-2-379, 384).CCLS.) ((427/430.1).CCLS.) ((438/125).CCLS.) ((206/308.1,524. 1,524.6,525,526,832).CCLS.) ((206/524.3).CCLS.)) and ((coat\$3	US-PGPUB; ⊎SPAT	OR	ON	2005/02/02 10:53
		or surfactant or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with ((wafer or chip or substrate or disc or disk) near2 (storage or storing or box or holder or holding or housing or carrier or cartridge)))				

	· ·			T		
L27	140	(surfactant or scourol) and (((wafer or chip or substrate or disc or disk) near2 (storage or storing or box or holder or holding or housing or carrier or cartridge or case)))	EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/02/02 10:56
L28	323	((coat\$3 or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer or wash\$3 or clean\$3) same ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holder or holding or housing or carrier))) same (surfactant or scourol)	US-PGPUB; USPAT	OR	ON	2005/02/02 10:57
L30	11	(((coat\$3 or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) same ((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holder or holding or housing or carrier))) same (antistatic\$3 or (anti adj static\$3) or ((prevent\$4 or eliminat\$3 or reduc\$5 or stop\$4 or lower\$3) near3 (dust or contamin\$5 or particle or particulate)))) and (((427/230,235).CCLS.) ((427/372.2,379, 384).CCLS.) ((427/430.1).CCLS.) ((438/125).CCLS.) ((206/308.1,524. 1,524.6,525,526,832).CCLS.) ((206/524.3).CCLS.))	US-PGPUB; USPAT	OR	ON	2005/02/02 10:58
131	42	((coat\$3 or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) same ((wafer or chip or substrate or disc or disk) near3 ((storage or storing or holding or housing or transport\$5) near2 (case or box or holder or carrier)))) same (antistatic\$3 or (anti adj static\$3) or ((prevent\$4 or eliminat\$3 or reduc\$5 or stop\$4 or lower\$3) near3 (dust or contamin\$5 or particle or particulate)))	US-PGPUB; USPAT	OR	ON	2005/02/02 10:59
L32	91	((coat\$3 or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) same ((wafer or chip or substrate or disc or disk) near3 ((storage or storing or holding or housing or transport\$5) near2 (case or box or holder or carrier)))) and (surfactant)	US-PGPUB; USPAT	OR	ON	2005/02/02 11:00

L33	0	(((((coat\$3 or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with (surfactant))) and (((427/230,235). CCLS.) ((427/352,353,354).CCLS.) ((427/372.2,379,384).CCLS.) ((427/430.1).CCLS.) ((438/125). CCLS.) ((206/308.1,524.1,524.6,525,526,832).CCLS.) ((206/524.3). CCLS.))) and ((wafer or chip or substrate or disc or disk) near3 ((storage or storing or holding or housing or transport\$5) near2 (case or box or holder or carrier))))	US-PGPUB; USPAT	OR	ON	2005/02/02 11:01
L34	57	(((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holder or holding or housing or carrier or cartridge or transport\$8))) and ((((coat\$3 or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with (surfactant))) and (((427/230,235).CCLS.) ((427/352, 353,354).CCLS.) ((427/430.1).CCLS.) ((438/125).CCLS.) ((206/308.1,524. 1,524.6,525,526,832).CCLS.) ((206/524.3).CCLS.)))	US-PGPUB; USPAT	OR	ON	2005/02/02 11:01
L35	48	((((coat\$3 or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with (surfactant))) and ((wafer or chip or substrate or disc or disk) near3 ((storage or storing or holding or housing or transport\$5) near2 (case or box or holder or carrier))))	US-PGPUB; USPAT	OR	ON	2005/02/02 11:02
L36	163	((coat\$3 or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) with (surfactant)) same ((prevent\$5 or eliminat\$3 or reduc\$5 or stop\$4 or lower\$3) near3 (dust\$3 or contamin\$8))	US-PGPUB; USPAT	OR	ON :	2005/02/02 11:03
L37	32	(((coat\$3 or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) near5 (surfactant))) and (((wafer or chip or substrate or disc or disk) near3 (storage or storing or case or box or holder or holding or housing or carrier or cartridge or transport\$8)))	EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/02/02 11:04

		<u> </u>				
L38	62	((coat\$3 or dip or dipped or dipping or immers\$4 or submer\$5 or deposit\$3 or film or layer) near3 (surfactant)) and ((prevent\$5 or eliminat\$3 or reduc\$5 or stop\$4 or lower\$3) near3 (dust\$3 or contamin\$8))	EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/02/02 11:05
L39	52	((coat\$3 deposit\$3 or film or layer) near5 (surfactant)) and (dust\$3 or contamin\$8) and dry\$3	EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/02/02 11:05
L40	395	(206/710,711).CCLS.	US-PGPUB; USPAT	OR	OFF	2005/02/02 11:17
L41	8	L40 and (surfactant)	US-PGPUB; USPAT	OR	ON	2005/02/02 11:17
L42	8	L40 and (surfactant)	US-PGPUB; USPAT	OR	ON	2005/02/02 11:17
L43	6263	(((wafer or chip or substrate or disc or disk) near2 (storage or storing or case or box or holder or holding or housing or carrier or cassette or transport\$6 or pod)) same (dust or particulate or particle or contamina\$6)) and ((coat\$4 or surfactant or deposit\$4 or film or layer or monolayer) near4 (storage or storing or case or box or holder or holding or housing or carrier or cassette or transport\$6 or pod))	US-PGPUB; USPAT	OR	ON	2005/02/02 11:34
L44	75	L43 and L15	US-PGPUB; USPAT	OR	ON	2005/02/02 11:26
L45	40	L43 and L40	US-PGPUB; USPAT	OR	ON	2005/02/02 11:26
L46	456	(((wafer or chip or substrate or disc or disk) near2 (storage or storing or case or box or holder or holding or housing or carrier or cassette or transport\$6 or pod)) same (dust or particulate or particle or contamina\$6)) and ((coat\$4 or surfactant or deposit\$4 or film or layer or monolayer) near6 (storage or storing or case or box or holder or holding or housing or carrier or cassette or transport\$6 or pod) with (prevent\$5 or eliminat\$5 or stop\$4 or reduc\$5 or minimiz\$6 or slow\$3) with (dust or particulate or particle or contamin\$8))	US-PGPUB; USPAT	OR	ON	2005/02/02 11:43

L47	123	(((wafer or chip or substrate or disc or disk) near2 (storage or storing or case or box or holder or holding or housing or carrier or cassette or transport\$6 or pod)) same (dust or particulate or particle or contamina\$6)) and ((coat\$4 or surfactant or deposit\$4 or film or layer or monolayer) near6 (storage or storing or case or box or holder or holding or housing or carrier or cassette or transport\$6 or pod) with (prevent\$5 or eliminat\$5 or stop\$4 or reduc\$5 or minimiz\$6 or slow\$3) with (dust or particulate or particle or contamin\$8))	EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/02/02 11:37
L48	31	(((wafer or chip or substrate or disc or disk) near2 (storage or storing or case or box or holder or holding or housing or carrier or cassette or transport\$6 or pod)) same (dust or particulate or particle or contamina\$6)) and ((coat\$4 or surfactant or deposit\$4 or film or layer or monolayer) near6 (storage or storing or case or box or holder or holding or housing or carrier or cassette or transport\$6 or pod) with (prevent\$5 or eliminat\$5 or stop\$4 or reduc\$5 or minimiz\$6 or slow\$3) with (dust or particulate or particle or contamin\$8)) and (dry\$4 near3 (coat\$3 or surfactant or film or layer or monolayer)) and ((clean\$4 or wash\$4 or rins\$5) with (H2O or "H.sub.2O" or water))	US-PGPUB; USPAT	OR	ON	2005/02/02 11:49
L49	1	L48 and L40	US-PGPUB; USPAT	OR	ON	2005/02/02 11:49

	,	· · · · · · · · · · · · · · · · · · ·				
L50		(((wafer or chip or substrate or disc or disk) near2 (storage or storing or case or box or holder or holding or housing or carrier or cassette or transport\$6 or pod)) same (dust or particulate or particle or contamina\$6)) and ((coat\$4 or surfactant or deposit\$4 or film or layer or monolayer) near6 (storage or storing or case or box or holder or holding or housing or carrier or cassette or transport\$6 or pod) with (prevent\$5 or eliminat\$5 or stop\$4 or reduc\$5 or minimiz\$6 or slow\$3) with (dust or particulate or particle or contamin\$8)) and (dry\$4 near3 (coat\$3 or surfactant or film or layer or monolayer)) and ((clean\$4 or wash\$4 or rins\$5) with (H2O or "H.sub.2O" or water))	EPO; JPO; DERWENT; IBM_TDB	OR	ON	2005/02/02 11:49
L51	0	(((wafer or chip or substrate or disc or disk) near2 (storage or storing or	EPO; JPO; DERWENT;	OR	ON	2005/02/02 11:49
		case or box or holder or holding or housing or carrier or cassette or	IBM_TDB			
		transport\$6 or pod)) same (dust or particulate or particle or				
		contamina\$6)) and ((coat\$4 or surfactant or deposit\$4 or film or				
na Ajija Karajija		layer or monolayer) near6 (storage or storing or case or box or holder			dut 50°y	
		or holding or housing or carrier or				
	1 19 19 19 19 19 19 19 19 19 19 19 19 19	cassette or transport\$6 or pod) with (prevent\$5 or eliminat\$5 or stop\$4				
		or reduc\$5 or minimiz\$6 or slow\$3)				
		with (dust or particulate or particle or contamin\$8)) and (dry\$4 near3				
1.5.		(coat\$3 or surfactant or film or			j di	
		layer or monolayer)) and ((clean\$4 or wash\$4 or rins\$5))				